

ABSTRACT

An apparatus providing identification, monitoring, and tracking of facilities maintenance in which an interactive information storage device receives and retains at least one facility profile that includes a facility identification, at least one process area descriptor and with at least one substrate associated with each process area descriptor. Each substrate includes a substrate condition, a substrate environment, a substrate process priority, and a substrate area. An analyzer evaluates the substrate condition, the substrate environment, and the substrate process priority to determine a substrate ranking. An estimator applies standard work information to the substrate condition, the substrate environment, the substrate process priority, and the substrate area, to determine a substrate maintenance estimate. A reporter generates maintenance specifications of the substrate maintenance estimates and substrate ranking for a selected one of the facility profiles. A method of identifying, monitoring, and tracking of facilities maintenance is disclosed.